



INFORMATION DISCLOSURE STATEMENT

#20 / IDS
8.7.03
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Applicant : Sophie et al.
App. No. : 09/975,466
Filed : October 9, 2001
For : IN SITU REDUCTION OF COPPER
OXIDE PRIOR TO SILICON CARBIDE
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Examiner : Kielin
Group Art Unit : 2813

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Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Enclosed is form PTO-1449 listing 1 reference that is also enclosed. This Information Disclosure Statement is being filed after a Request for Continued Examination under §1.114 and before the mailing date of a first Office Action on the merits, and presumably no fee is required in accordance with 37 C.F.R. § 1.97(b)(4). If a first Office Action on the merits was mailed before the mailing date of this Statement, the Commissioner is authorized to charge the fee set forth in 37 C.F.R. § 1.17(p) to Deposit Account No. 11-1410.

Respectfully submitted,

KNOBBE, MARTENS, OLSON & BEAR, LLP

Dated: July 21, 2003By: 

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